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₽Title: JP08338546A2: PRESSURE TYPE FLOW CONTROL DEVICE

PDerwent Title: Pressure type flow rate control appts. used in semiconductor and chemical

manufacturing plants - adjusts orifice upstream side pressure by opening and closing control valve, to control orifice downstream side flow rate

[Derwent Record]

PCountry:

JP Japan

A (See also: <u>JP03291161B2</u>)

PInventor:

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PAssignee:

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Published / Filed:

1996-12-24 / 1995-06-12

PApplication

JP1995000144722

Number:

₽ IPC Code: F16K 17/22;

Priority Number:

1995-06-12 JP1995000144722

PAbstract:

PURPOSE: To heighten the control accuracy of a flow control

device and to reduce the size and cost of the device.

CONSTITUTION: A pressure type flow control device is adapted to control the flow of a fluid by keeping the orifice upstream side pressure about two or more times as large as the downstream side pressure. The flow control device comprises an orifice 5, a control valve 2 disposed on the upstream side thereof, a pressure detecting device 3 disposed between the control valve 2 and the orifice 5, and an arithmetic control device 6 for computing the flow from the detected pressure P1 of the pressure detecting device 3 as Qc=KP1 (wherein K is a constant) and outputting a difference

between a flow command signal Qs and the computed flow Qc as a control signal Qy to the driving part of the control valve 2. The pressure P1 is regulated by opening and closing the control valve 2 to control the downstream side flow of the orifice 5.

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None

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References:

PDF	Patent	Pub.Date	Inventor	Assignee	Title
28	<u>US6450190</u>	2002-09-17	Ohmi; Tadahiro		Method of detecting abniflow rate in pressure-type
	<u>US6158679</u>	2000-12-12	Ohmi; Tadahiro		Orifice for pressure type control unit and process manufacturing orifice

8 Other Abstract Info:

DERABS G97-036302







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(57) Abstract:

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a flow command signal Qs and the computed flow Qc as a control signal Qy to the driving part of the control valve 2. The pressure P₁ is regulated by opening and closing the control valve 2 to control the downstream side flow of the orifice 5.

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